

**12<sup>th</sup> US-Japan Seminar on Dielectric and Piezoelectric Ceramics**  
**November 6–9, 2005**  
**Annapolis Marriott Waterfront Hotel, Annapolis, Maryland, USA**

**PROGRAM**

Meeting: Chesapeake Ballroom

Posters: Ballroom Foyer

**Sunday, November 6**

5:00–8:00 p.m.     *Registration (Foyer)*  
7:30–9:00 p.m.     *Welcome Reception (Chesapeake Ballroom South)*

**Monday, November 7**

7:00–8:00 a.m.     *Registration (Foyer); Continental Breakfast (Patio)*  
8:00–8:15 a.m.     *Introduction and Welcome*  
                         Carl Wu, US General Chair, and  
                         Hiroshi Kishi, Japan General Chair

**SESSION I. Basic and Fundamental Science of  
Dielectric and Piezoelectric Materials**

Session Chairs:   Stephen Streiffer, *Argonne National Laboratory (USA)*  
                         Tadashi Takenaka, *Tokyo University of Science (Japan)*

8:15–9:15 a.m.     *Plenary Lectures — Basic and Fundamental Science of Dielectric and Piezoelectric Materials*

PI.1   8:15 – 8:45 a.m.     First principles calculations, crystal chemistry and properties of ferroelectric perovskites; Ilya Grinberg and Andrew Rappe; *University of Pennsylvania, USA.*

PI.2   8:45 – 9:15 a.m.     Cooling-Rate-Dependent Domain Structures of PMN-xPT Single Crystals Observed by Contact Resonance Piezoresponse Force Microscope; Takashi Yamamoto, Junichi Sakamoto and Hirotake Okino; *National Defense Academy, Japan.*

9:15 – 9:30 a.m.     *Break (Patio)*

9:30 a.m. – 12:00 p.m.     *Poster Summaries and Poster Viewing*

## **Basic Science of Dielectrics**

- I.1 Improved Mixing Rule on Permittivity; Kikuo Wakino; *Murata Manufacturing Company Ltd., Japan.*
- I.2 Atomic Level Control of Perovskite Lattice Instabilities by Cation Substitution; David J. Singh<sup>\*</sup>, M. Ghita<sup>†</sup>, M. Fornari<sup>†</sup>, and S.V. Halilov<sup>#</sup>; <sup>\*</sup>*Oak Ridge National Laboratory*, <sup>†</sup>*Central Michigan University*, and <sup>#</sup>*R.J. Mears LLC, USA*.
- I.3 Effect of Cation Ratio on Defect Structure and Related Properties of Lithium Niobate – Lithium Ion Diffusion in LN – ; Hajime Haneda, Isao Sakaguchi, Shunji Takekawa, Masaru Nakamura, and Kenji Kitamura; *National Institute for Materials Science, Advance Materials Laboratory, Japan.*
- I.4 Influence of Vacancies on the Dielectric Properties of HfO<sub>2</sub>; Eric Cockayne; *National Institute of Standards and Technology, USA.*
- I.5 Dielectric Relaxation of BaTiO<sub>3</sub>-based Ceramics; Takaaki Tsurumi, J. Li, H. Kakemoto, S. Wada and H. Kawaji; *Tokyo Institute of Technology, Japan.*
- I.6 First-Principles Based Simulations of the Relaxor Ferroelectrics PSN and PMN; Benjamin Burton<sup>\*</sup>, Eric Cockayne<sup>\*</sup>, S. Tinte<sup>\*</sup>, and U.V. Waghmare<sup>†</sup>; <sup>\*</sup>*National Institute of Standards and Technology, USA*, <sup>†</sup>*J. Nehru Center for Advanced Scientific Research, India.*
- I.8 Apparent Colossal Dielectric Relaxation by Electrical Heterogeneous Structure; Mamoru Fukunaga; *Waseda University, Japan.*
- I.9 Polarization Rotation in Relaxor Ferroelectrics: Advances in First-principles Studies of Transducer Materials; Ronald E. Cohen<sup>\*</sup>, Z. Wu<sup>\*</sup>, N. Choudhury<sup>\*†</sup>, and A. Asthagiri<sup>\*#</sup>; <sup>\*</sup>*Carnegie Institute of Washington, USA*, <sup>#</sup>*University of Florida, USA*, and <sup>†</sup>*Bhabha Atomic Research Centre, India.*
- I.10 Ferroelectric Systems with Ultra-Low Domain Wall Energy: PMN-PT and PZN-PT Near the Morphotropic Boundary; A.G. Khachaturyan<sup>\*</sup> and <sup>†</sup>D. Viehland; <sup>\*</sup>*Rutgers University*, <sup>†</sup>*Virginia Polytechnic Institute, USA*.
- I.11 Electric-field-induced transformation of incommensurate modulations in antiferroelectric Pb<sub>0.99</sub>Nb<sub>0.02</sub>[Zr<sub>0.58</sub>Sn<sub>0.42</sub>)<sub>0.955</sub>Ti<sub>0.045</sub>]<sub>0.98</sub>O<sub>3</sub>; Xiaoli Tan<sup>\*</sup>, Hui He<sup>\*</sup>, and David P. Cann<sup>†</sup>; <sup>\*</sup>*Iowa State University*, <sup>†</sup>*Oregon State University*<sup>†</sup> *USA*.
- I.12 Relaxor Ferroelectric Polymers; Shihai Zhang<sup>\*</sup>, Cheng Huang<sup>\*</sup>, Z.-Y. Cheng<sup>†</sup>, F. Xia<sup>\*</sup>, R. Klein<sup>\*</sup>, Q. M. Zhang<sup>\*</sup>, V. Bobnar<sup>†</sup>, A. Levstik<sup>†</sup>, and Francois Bauer<sup>#</sup>; <sup>\*</sup>*The Pennsylvania State University, USA*, <sup>†</sup>*Auburn University, USA*, <sup>†</sup>*Josef Stefan Institute, Slovenia*, <sup>#</sup>*Institut Franco-Allemand de Recherches de Saint-Louis, (ISL), France*.
- I.13 Phase Transformation of Fine Powder of Barium Titanate Confirmed by Raman Spectroscopy and Powder X-Ray Diffraction; Tooru Nakai, Hiroyuki Ikawa, Seiichi Higuchi, and Minoru Takemoto; *Kanagawa Institute of Technology, Japan.*
- I.14 Nanograin Barium Titanates Ceramics, Processing and Properties; I-Wei Chen; *University of Pennsylvania, USA*.

- I.15 Size and Temperature Dependence of Crystal Structures on Barium Titanate Nanoparticles; Takuya Hoshina, Hirofumi Kakemoto, Takaaki Tsurumi, and Satoshi Wada; *Tokyo Institute of Technology, Japan.*
- I.16 Effect of Oxygen Partial Pressure on Sintering Undoped Nanocrystalline Barium Titanate Powder; Anton Polotai<sup>\*</sup>, Kristen Breece<sup>\*</sup>, Elizabeth Dickey<sup>\*</sup>, Vadim Bulanov<sup>†</sup>, Andrey Ragulya<sup>†</sup>, and Clive Randall<sup>\*</sup>; <sup>\*</sup>*The Pennsylvania State University, <sup>†</sup>NAS of Ukraine), USA.*
- I.17 Multi-polarization-mechanism in polar dielectrics and dielectric behavior under dc bias; Ang Chen and Zhi Yu; *The University of Akron, USA.*
- I.18 Dielectric relaxor behavior in doped quantum paraelectrics and related dielectrics; Zhi Yu and Ang Chen; *The University of Akron, USA.*
- I.19 Electrospinning of Complex Oxide Ceramic Nanofibers; Juan C. Nino, Junhan Yuh, and Wolfgang M. Sigmund; *University of Florida, USA.*
- I.20 Flexoelectricity Beyond the Transverse Effect; Wenyi Zhu, Nan Li, and L. Eric Cross; *The Pennsylvania State University, USA.*
- I.21 The polar cluster like behavior in Ti<sup>4+</sup> doped Ba(ZrTi)O<sub>3</sub> ceramics; Tanmoy Maiti<sup>\*</sup>, E. Alberta<sup>†</sup>, R. Guo<sup>\*</sup>, and Amar Bhalla<sup>\*</sup>; *The Pennsylvania State University, <sup>†</sup>TRS Ceramics, USA.*

12:00 – 1:00 p.m.      *Lunch (Patio)*

## **SESSION II. Piezoelectric Materials, Phenomena, and Applications**

Session Chairs:    Takaaki Tsurumi, *Tokyo Institute of Technology (Japan)*  
Ahmad Safari, *Rutgers University (USA)*

1:00–2:30 p.m.      *Plenary Lectures – Piezoelectric Materials, Phenomena, and Applications*

- PII.1    1:00 – 1:30 p.m.      Recent developments in Electromechanical Probing on the Nanoscale: Vector and Spectroscopic Imaging, Resolution, and Molecular Orientation Mapping; Sergei V. Kalinin<sup>\*</sup>, S. Jesse<sup>\*</sup>, A.Y. Borisevich<sup>\*</sup>, H.N. Lee<sup>\*</sup>, B.J. Rodriguez<sup>\*</sup>, J. Hanson<sup>†</sup>, A. Gruverman<sup>†</sup>, E. Karapetian<sup>#</sup>, and M. Kachanov<sup>\*\*</sup>; <sup>\*</sup>*Oak Ridge National Laboratory*, <sup>†</sup>*North Carolina State University*, <sup>#</sup>*Suffolk University*, and <sup>\*\*</sup>*Tufts University, USA.*
- PII.2    1:30 – 2:00 p.m.      Nb-Perovskite Structured Piezoelectric Ceramics for Sensor and Actuator; Yasuyoshi Saito and Hisao Takao ; *Toyota Central R&D Labs, Japan.*
- PII.3    2:00 – 2:30 p.m.      Piezoelectric Multi-Layer Ceramic Components: Current Status and Future Trends; Heinz Florian; *EPCOS OHG, Austria (Europe).*
- 2:30 – 2:45 p.m.      *Break/Group Photo (Patio) (in case of rain, Group Photo will be taken at 5:30 PM in the Chesapeake Ballroom)*
- 2:45 – 5:30 p.m.      *Poster Summaries and Poster Viewing*

## ***Piezoelectric Materials, Phenomena, and Applications***

- II.1 Enhanced Tetragonality in PbTiO<sub>3</sub>-Bi(B'B'')O<sub>3</sub> Solid Solutions; Matthew R. Suchomel and Peter K. Davies; *University of Pennsylvania, PA, USA.*
- II.2 Application of BSPT high temperature ceramics for acceleration sensors; Sorah Rhee<sup>\*</sup>, J. Suzuki<sup>\*</sup>, S.J. Zhang<sup>†</sup>, and T.R. Shroud<sup>†</sup>; <sup>\*</sup>MEGGITT Endevco Inc., and <sup>†</sup>Penn State University, USA.
- II.3 Piezoelectric Properties of Textured Ceramics in Bismuth Layer-structured Ferroelectrics; Masahiko Kimura, Hirozumi Ogawa, Takuya Sawada, Kosuke Shiratsuyu, Nobuyuki Wada, and Akira Ando, *Murata Manufacturing Co., Ltd.*
- II.4 Crystal-oriented Sr<sub>2</sub>NaNb<sub>5</sub>O<sub>15</sub> Ceramics Fabricated by High-Magnetic-Field Method; Yutaka Doshida<sup>\*</sup>, Hiroshi Kishi<sup>\*</sup>, Yusuke Hattori<sup>†</sup>, Atsushi Makiya<sup>†</sup>, Satoshi Tanaka<sup>†</sup>, Keizo Uematsu<sup>†</sup>, Tsunehisa Kimura<sup>#</sup>; <sup>\*</sup>Taiyo Yuden Co., Ltd., <sup>†</sup>Nagaoka University of Technology, <sup>#</sup>Tokyo Metropolitan University, Japan.
- II.5 Longitudinal Elastic Properties of Morphotropic PMN-PT Single Crystal; Lynn Ewart, Elizabeth McLaughlin, Hal Robinson, and Ahmed Amin; *NAVSEA Undersea Warfare Center Division Newport, USA.*
- II.7 Mechanisms of “Solid State” Single Crystal Conversion; Shen Dillon<sup>\*</sup>, Edward P. Gorzkowski<sup>†</sup>, Helen M. Chan<sup>\*</sup>, Martin P. Harmer<sup>\*</sup>; <sup>\*</sup>Lehigh University, <sup>†</sup>Naval Research Laboratory, USA.
- II.8 Spark-Plasma Sintering of PMN-PT Ceramics for Solid State Single Crystal Growth; Hisao Yamada; *Cerone, Inc., USA.*
- II.9 Preparation and Piezoelectric Properties of 2 Inch Size Relaxor Single Crystals; Noboru Ichinose and Kentaro Hirayama; *Waseda University, Japan.*
- II.10 Relationship between Crystal Plane and Poling Direction to Realize Giant Electromechanical Coupling Factor of k<sub>31</sub> Mode in Relaxor Single Crystals; Toshio Ogawa; *Shizuoka Institute of Science and Technology, Japan.*
- II.11 Dielectric, Elastic, Piezoelectric Constants and Surface Acoustic Wave Properties of Rare-Earth Calcium Oxborates, RCa<sub>4</sub>O(BO<sub>3</sub>)<sub>3</sub> (R = La, Gd, Y), Single Crystals; Hiroyuki Shimizu<sup>\*</sup>, Ayako Kondo<sup>\*</sup>, Masahiro Nishida<sup>†</sup>, Hiroaki Takeda<sup>\*</sup>, Takashi Nishida<sup>\*</sup>, and Tadashi Shiosaki<sup>\*</sup>; <sup>\*</sup>Nara Institute of Science and Technology (NAIST), <sup>†</sup>Sakai Chemical Industry Co., Ltd. <sup>†</sup>Japan.
- II.12 High Density Deformable Mirror Technology; Shoko Yoshikawa, Thomas Price, Jeffery Cavaco, and Mark Ealey; *Xinetics, Inc., USA.*
- II.13 Ferroelectric and Piezoelectric Properties of (Bi<sub>1/2</sub>K<sub>1/2</sub>)TiO<sub>3</sub> Ceramics; Yuji Hiruma, Rintaro Aoyagi, Hajime Nagata and Tadashi Takenaka; *Tokyo University of Science, Japan.*
- II.14 High Dielectric Constant and Large Electromechanical Coupling Factor Relaxor-Based Piezoelectric Ceramics; Yohachi (John) Yamashita & Yasuharu Hosono; *Toshiba Corporation, Japan.*
- II.16 Opportunities in Crystal Growth and Applications of PMN-PT Piezo Crystal; Pengdi Han; *H.C. Materials Corporation, USA.*

- II.17 Temperature dependence of electrical and electromechanical properties of  $\text{Ba}(\text{Zr}_{0.2}\text{Ti}_{0.8})\text{O}_3$  thin films by chemical solution deposition; *Takashi Hayashi, Kohei Ohashi, and Hiroshi Maiwa, Shonan Institute of Technology, Japan.*
- II.18 Characterization and process control of Ag interdiffusion into multilayer PZT actuators; *Niall Donnelly, Thomas R. Shrout, and Clive A. Randall; The Pennsylvania State University, USA.*
- II.19 High strain response in donor doped  $\text{BaTiO}_3$  with gradient structures; *Relva Buchanan, C.Y. Yau, Euisuk Park, and Rajesh Surana, University of Cincinnati, USA.*
- II.20 Domain Wall Engineering for Lead-free Piezoelectric Crystals; *Satoshi Wada, Koichi Yako, Keiichi Yokoo, Hirofumi Kakemoto, and Takaaki Tsurumi; Tokyo Institute of Technology, Japan.*
- II.21 Theoretical analysis on domain size dependence of piezoelectric properties in domain engineered ferroelectric crystals; *Wenwu Cao<sup>\*</sup> and Rajeev Ahluwalia<sup>†</sup>; \*The Pennsylvania State University, <sup>†</sup>Los Alamos National Laboratory, USA.*

7:00–9:00 p.m. *Dinner (Chesapeake Ballroom) – “Electroceramic Bridge Building Awards Banquet”*  
*2005 Awardees: Noboru Ichinose and Kikuo Wakino (Japan);*  
*L. Eric Cross and Robert Pohanka (U.S.)*

## **Tuesday, November 8**

7:30 a.m. *Continental Breakfast (Patio)*

### **SESSION III. Multifunctional Materials, Microwave, and Optical Materials**

Session Chairs: *Takashi Yamamoto, National Defense Academy (Japan)*  
*Susan Trolier-McKinstry, The Pennsylvania State University (USA)*

8:30–9:30 a.m. *Plenary Lectures – Multifunctional Materials, Microwave, and Optical Materials*

- PIII.1 8:30 – 9:00 a.m. Multiferroic Materials with Polarization; *Shuxiang Dong, Junyi Zhai, Zhengping Xing, Jie-Fang Li, and D. Viehland; Virginia Polytechnic Institute, USA.*
- PIII.2 9:00 – 9:30 a.m. Embedded Ceramic Passive on Printed Wiring Board Using Aerosol Deposition; *Yoshihiko Imanaka<sup>\*</sup> and Jun Akedo<sup>†</sup>; \*Fujitsu Limited, <sup>†</sup>National Institute of Advanced Industrial Science and Technology, Japan.*

9:30 – 9:45 a.m. *Break (Patio)*

9:45 a.m. – 12:30 p.m. *Poster Summaries and Poster Viewing*

### **Multifunctional Materials, Microwave, and Optical Materials**

- III.1 High Speed Optical Micro-Scanner Fabricated by Aerosol Deposition; J. Akedo, M. Lebedev, and J. Park; *National Institute of Advanced Science and Technology, Japan*.
- III.2 New ferromagnetic ferroelectric  $\text{Bi}_2\text{NiMnO}_6$  compound with double-perovskite structure; Yuichi Shimakawa, Masaki Azuma, Kazuhide Takata, Masayuki Hashisaka, Daisuke Kan, Atsunobu Masuno, Maiko Sakai, Takahito Terashima, Ko Mibu, and Mikio Takano; *Kyoto University, Japan*.
- III.3 Multiferroic Self-Assembled Nanostructures in Epitaxial Films; Igor Levin<sup>\*</sup>, J. Slutsker<sup>\*</sup>, J. Li<sup>\*†</sup>, and A. Roytburd<sup>†</sup>; <sup>\*</sup>*National Institute of Standards and Technology* and <sup>†</sup>*University of Maryland, USA*.
- III.4 Enhancement of Insulating and Ferroelectric Properties of Bismuth Ferrite Thin Films by Ion-substitution; Hiroshi Uchida<sup>\*</sup>, Shintaro Yasui<sup>\*</sup>, Risako Ueno<sup>†</sup>, Hiroshi Funakubo<sup>†</sup>, and Seiichiro Koda<sup>\*</sup>; <sup>\*</sup>*Sophia University*, <sup>†</sup>*Tokyo Institute of Technology, Japan*.
- III.5 Magnetically tunable dielectric materials; Gavin Lawes<sup>\*</sup>, T. Kimura<sup>\*\*</sup>, C.M. Varma<sup>\*\*\*</sup>, M.A. Subramanian<sup>†</sup>, R.J. Cava<sup>#</sup>, and A.P. Ramirez<sup>##</sup>; <sup>\*</sup>*Wayne State University*, <sup>\*\*</sup>*Los Alamos National Laboratory*, <sup>\*\*\*</sup>*University of California Riverside*, <sup>†</sup>*Dupont Central Research and Development*, <sup>#</sup>*Princeton University*, <sup>##</sup>*Bell Laboratories, Lucent Technologies, USA*.
- III.6 Dielectric permittivity mapping with non-contact microwave probe for dielectric materials; Hirofumi Kakemoto, Takakiyo Harigai, Song-Min Nam, Satoshi Wada and Takaaki Tsurumi; *Tokyo Institute of Technology, Japan*.
- III.7 Microwave Propagation Through the Dielectric Resonator Arrays; Masato Iwasaki<sup>\*†</sup> Steve Perini<sup>\*</sup>, Elena Semouchkina<sup>\*</sup>, George Semouchkin<sup>\*</sup>, Khalid Rajab<sup>\*</sup>, Eugene Furman<sup>\*</sup>, Masahiko Okuyama<sup>†</sup>, Clive Randall<sup>\*</sup>, and Michael Lanagan<sup>\*</sup>; <sup>\*</sup>*The Pennsylvania State University, USA*, <sup>†</sup>*NGK Spark Plug Co. Ltd., Japan*.
- III.8 Silicates with Low Permittivity for Millimeterwave Dielectrics; Hitoshi Ohsato<sup>\*</sup>, Tsutomu Tsunooka<sup>\*</sup>, Tomonori Sugiyama<sup>\*</sup>, Mio Terada<sup>\*</sup>, Yi-Ping Guo<sup>\*</sup>, Keizou Kawamura<sup>†</sup> and Ken-ichi Kakimoto<sup>\*</sup>; <sup>\*</sup>*Nagoya Institute of Technology* and <sup>†</sup>*Taiyo Yuden Co., Ltd., Japan*.
- III.9 New Developments in Ceramic Metamaterials; Khalid Z. Rajab, Elena Semouchkina, George Semouchkin, Clive Randall, Amanda Baker, Masato Iwasaki, Raj Mittra, and Michael T. Lanagan; *The Pennsylvania State University, USA*.
- III.10 Optical Properties of Transparent Ceramics, Nobuhiko Tanaka, Yuji Kintaka, Satoshi Kuretake, Akira Ando, and Yukio Sakabe; *Murata Manufacturing Co., Ltd., Japan*.
- III.11 Measurement of complex permittivity in dielectric materials using a free space method; Youngjoon An<sup>\*</sup>, Takashi Yamamoto<sup>\*</sup>, Hirotake Okino<sup>\*</sup>, Takeshi Deguchi<sup>†</sup>, and Shunkichi Ueda<sup>†</sup>; <sup>\*</sup>*National Defense Academy*, <sup>†</sup>*Osaka Laboratory/Tayca Co., Japan*.

- III.12 Optical Probes of Strained Ferroelectric Thin Films; *Hongzhou Ma\**, *P. Irvin\**, *J.H. Haeni\*\**, *W. Chang†*, *R. Uecker††*, *P. Reiche ††*, *Y. Li\*\**, *S. Choudhury\*\**, *W. Tian#*, *M.E. Hawley##*, *B. Craigο^*, *A.K. Tagantsev^*, *X.Q. Pan#*, *S.K. Streiffer^*, *L.Q. Chen\*\**, *S.W. Kirchoefer†*, *D.G. Schlom\*\**, and *Jeremy Levy\**; <sup>\*</sup>*University of Pittsburgh, USA*, <sup>\*\*</sup>*Penn State University, USA*, <sup>†</sup>*Naval Research Laboratory, USA*, <sup>††</sup>*Institute for Crystal Growth, Berlin, Germany*, <sup>#</sup>*University of Michigan*, <sup>##</sup>*Los Alamos National Laboratory*, <sup>^</sup>*Motorola Labs*, <sup>^</sup>*Ecole Polytechnique de Fédérale de Lausanne, Switzerland*, and <sup>^</sup>*Argonne National Laboratory*.
- III.15 Paraelectric Thin Films with Engineered Misfit Strain and Anisotropic Epitaxy; *W. K. Simon\**, *E.K. Akdogan\**, *Ahmad Safari\**, and *J.A. Bellotti†*; *Rutgers University*, <sup>†</sup>*Naval Research Laboratories, USA*.
- III.16 Interrelation between Dielectric Property and Elastic Property of Ceramics of Nominal Composition  $(\text{Ba}_{1-x}\text{Ca}_x)(\text{Mg}_{1/3}\text{Ta}_{2/3})\text{O}_3$ ; *Hiroyuki Ikawa\**, *Michio Yamashiro\**, *Mikio Fukuhara†*, and *Minoru Takemoto\**; <sup>\*</sup>*Kanagawa Institute of Technology*, <sup>†</sup>*Tohoku University, Japan*.
- III.17  $\text{Bi}_{1.5}\text{Zn}_{1.0}\text{Nb}_{1.5}\text{O}_7$  Thin Films for Tunable Microwave Applications; *Susanne Stemmer\**, *Jiwei Lu\**, *Jaehoon Park\**, *Robert A. York\**, and *Alexander K. Tagantsev†*; <sup>\*</sup>*University of California-Santa Barbara, USA*, <sup>†</sup>*Ecole Polytechnique Fédérale de Lausanne (EPFL), Lausanne, Switzerland*.
- III.18 Comparative Phase Equilibria in the  $\text{Bi}_2\text{O}_3\text{-MO}_x\text{-Nb}_2\text{O}_5$  Systems ( $\text{MO}_x = \text{Mn}_2\text{O}_3$ ,  $\text{Fe}_2\text{O}_3$ ,  $\text{Co}_3\text{O}_4$ ,  $\text{ZnO}$ ); *Terrell Vanderah\**, *M.W. Lufaso\**, *A.U. Adler\**, *I.M. Pazos\**, and *S.M. Bell†*; <sup>\*</sup>*National Institute of Standards and Technology (NIST)*, <sup>†</sup>*TCI Ceramics, Inc. USA*.
- III.19 Synthesis and Structural Characterization of  $\text{Bi}(\text{Fe}_x\text{Al}_{1-x})\text{O}_3$  Thin Films; *Takeshi Yoshimura*, *Morihiro Okada*, *Norifumi Fujimura*; *Osaka Prefectural University, Japan*.
- III.20 Products and Microwave Dielectric Properties and Abnormally Wide Solid Solution Range of the  $(\text{Ba}_{1-x}\text{Ca}_x)(\text{Sc}_{1/2}\text{Nb}_{1/2})\text{O}_3$  System; *Yuya Fujii*, *Minoru Takemoto*, *Michinori Takayama*, *Jun Katagiri*, *Daisuke Satoh*, *Ryo Hirukawa*, and *Hiroyuki Ikawa*; *Kanagawa Institute of Technology, Japan*.
- III.21 Microwave Electrooptic Coefficient and Modulation Applications Using Ferroelectric Single Crystal Fibers; *Chuanyong Huang*, *Jonathan Taylor*, *Amar Bhalla*, and *Ruyan Guo*; *The Pennsylvania State University, USA*.

12:30–1:30 p.m.      *Lunch (Patio)*

#### SESSION IV. Dielectric Capacitor Materials

Session Chairs:      *Masatoshi Adachi, Toyama Prefectural University (Japan)*  
*I. Wei Chen, University of Pennsylvania (USA)*

1:30–2:30 p.m.      *Plenary Lectures – Dielectric Capacitor Materials*

- PIV.1 1:30 – 2:00 p.m.      Interfacial Defect Chemistry in Electroceramics: Complementary Analytical Transmission Electron Microscopy and Impedance Spectroscopy Studies; *Elizabeth C. Dickey*, *Clive A. Randall*, *Gai-Ying Yang*, and *Oomman Varghese*; *The Pennsylvania State University, USA*.

PIV.2 2:00 – 2:30 p.m. Residual Stress and Electrical Performance of Multilayer Ceramic Capacitors; Yukie Nakano, Takeshi Nomura, and Atsushi Hitomi; TDK Corporation, Japan.

2:30 – 2:45 p.m. *Break (Patio)*

2:45 – 6:15 p.m. *Poster Summaries and Poster Viewing*

### **Dielectric Capacitor Materials**

- IV.1 The Synthesis and Property of CaZrO<sub>3</sub> by Using Ultra Fine and Highly Dispersed CaCO<sub>3</sub>; Jin Amagai<sup>\*</sup>, Yuzo Kato<sup>\*</sup>, Akira Ueki<sup>\*</sup>, Noriko Saito<sup>†</sup>, Naoki Ohashi<sup>†</sup>, Hajime Haneda<sup>†</sup>; <sup>\*</sup>Ube Material Industries, Ltd., <sup>†</sup>NIMS, Japan.
- IV.2 Effect of Manganese Distribution on Properties of CaZrO<sub>3</sub>-Based Ceramics, Pascal Pinceloup, A. Gurav, and M. Randall; KEMET Electronics Corporation, USA.
- IV.3 Microcontact Printed Thin Film Capacitors; H. Nagata<sup>\*</sup>, S.W. Ko<sup>\*</sup>, Susan Trolier-McKinstry<sup>\*</sup>, C.A. Randall<sup>\*</sup>, P. Pinceloup<sup>†</sup>, J. Beeson<sup>†</sup>, D. Skamser<sup>†</sup>, M. Randall<sup>†</sup>, and A. Tajuddin<sup>†</sup>; <sup>\*</sup>The Pennsylvania State University, <sup>†</sup>Kemet Electronics Corp., USA.
- IV.4 Effects of the Printed Wiring Board Process on Ceramic Thin-Film Capacitors Integrated into Printed Wiring Boards; William Borland<sup>\*</sup>, J.J. Barnes<sup>\*</sup>, S.H. Zhang<sup>\*</sup>, J.P. Maria<sup>†</sup>, B. Laughlin<sup>†</sup>, and J.F. Ihlefeld<sup>†</sup>; <sup>\*</sup>Dupont Electronic Technologies and <sup>†</sup>North Carolina State University, USA.
- IV.5 PLZT Film-on-Foil Capacitors for Embedded Passives; David Kaufman, S. Saha, and K. Uprety; Argonne National Laboratory, USA.
- IV.6 High-K CuCu<sub>3</sub>Ti<sub>4</sub>O<sub>12</sub> Dielectrics; David Cann<sup>\*</sup>, Eric Patterson<sup>†</sup>, Seunghwa Kwon<sup>\*</sup>, Chien-Chih Huang<sup>\*</sup>, and Steve W. Martin<sup>†</sup>; <sup>\*</sup>Oregon State University, <sup>†</sup>Iowa State University, USA.
- IV.7 The Effect of Sintering Conditions and Starting Powders on the Giant Dielectric Properties of CaCu<sub>3</sub>Ti<sub>4</sub>O<sub>12</sub>; Barry Bender and Ming-Jen Pan; U.S. Naval Research Laboratory, USA.
- IV.8 Effects of Interlayer Diffusion on the Dielectric Properties of Multilayer Structures; Ming-Jen Pan, Barry A. Bender, and Edward Gorzkowski; U.S. Naval Research Laboratory, USA.
- IV.9 Complex Permittivity Model of Barrier Layer Capacitor with Bimodal Grain Size Distribution; Ming-Jen Pan, Barry A. Bender, and Edward Gorzkowski; U.S. Naval Research Laboratory, USA.
- IV.10 Mechanism of Capacitance Aging Under DC-field in X7R-MLCCs; Takaaki Tsurumi, M. Shono, H. Kakemoto and S. Wada; Tokyo Institute of Technology, Japan.
- IV.11 Interfacial Reactions in Ni-BaTiO<sub>3</sub> Base Metal Electrode Multilayer Ceramic Capacitors (BME-MLCCs); Gaiying Yang, S.I. Lee, Z. K. Liu, C. Anthony, E. C. Dickey, and C. A. Randall; The Pennsylvania State University, USA.

- IV.12 The {111} modulated domains in X7R formulated BaTiO<sub>3</sub> multilayer ceramic capacitors; *Yu-Chuan Wu*<sup>\*</sup>, *Daniel E. McCauley*<sup>†</sup>, *Mike Chu*<sup>†</sup>, and *Hong-Yang Lu*<sup>\*†</sup>; <sup>\*</sup>National Sun-Yat Sen University (Taiwan) and <sup>†</sup>Ferro Corp., USA.
- IV.13 Effect of Re-oxidation on Dielectric Properties in Ni-MLCC; *Hiroshi Kishi*, *Youichi Mizuno*, *Tomoya Hagiwara* and *Hirokazu Orimo*; *Taiyo Yuden Co., Ltd.*, Japan.
- IV.14 Effect of Dielectric Thickness on the dc and ac Dielectric Breakdown for Low Fired COG and X7R MLC Capacitors; *Galeb H. Maher*, *James M. Wilson* and *Samir G. Maher*; *MRA Laboratories, Inc.*, USA.
- IV.15 Structural Analysis of Eu and Nd Substitution for BaTiO<sub>3</sub> Ceramics; *Takanori Ishikawa*<sup>\*</sup>, *Kenji Ohnuma*<sup>\*</sup>, *Ken-ichi Kakimoto*<sup>\*</sup>, *Hitoshi Ohsato*<sup>\*</sup>, and *Youichi Mizuno*<sup>†</sup>; <sup>\*</sup>Nagoya Institute of Technology and <sup>†</sup>Taiyo Yuden Co., Ltd., Japan.
- IV.16 PO<sub>2</sub> Dependence of the Diffuse Phase Transition in Base Metal Capacitor Dielectrics; *Daniel E. McCauley*, *Mike S.H. Chu*, and *Mohammed H. Megherhi*; *Ferro Electronics Corporation*, USA.
- IV.17 Electric Conduction of Thin-layer Ni-MLCCs with Core-Shell Structure; *Koichiro Morita*<sup>\*†</sup>, *Youichi Mizuno*<sup>\*</sup>, *Hirokazu Chazono*<sup>\*</sup>, *Hiroshi Kishi*<sup>\*</sup>, *G. Y. Yang*<sup>†</sup>, *E. Dickey*<sup>†</sup>, *C. A. Randall*<sup>†</sup>; <sup>\*</sup>Taiyo Yuden Co., Ltd. (Japan), <sup>†</sup>The Pennsylvania State University, USA.
- IV.18 Factors in Improved DC Bias Performance in X7R Capacitors; *Craig Nies* and *Marianne Berolini*; *AVX Corp.*, USA.
- IV.19 New Development in Copper Compatible Base Metal Dielectric Formulations; *Mohammed H. Megherhi*, *Walt J. Symes*, *Mike S.H. Chu*, and *Daniel E. McCauley*; *Ferro Electronic Materials Systems*, USA.
- IV.20 Barium-titanate-based lead-free materials for capacitor and PTCR use far beyond 130°C; *Tadashi Shiosaki*, *Hiroaki Takeda*, *Ryuhei Goto*, and *Takashi Nishida*; *Nara Institute of Science & Technology (NAIST)*, Japan.
- IV.21 The Role of Anion Impurities in Barium Titanate; *Ian Burn*; *IBC, Inc.*, USA.
- IV.22 The Effect of Grain Size on the Thin Layer BME X7R Dielectrics; *Xilin Xu*<sup>\*</sup>, *P. Pinceloup*<sup>\*</sup>, *J. Beeson*<sup>\*</sup>, *A. Gurav*<sup>†</sup>, and *G.Y. Yang*<sup>†</sup>; <sup>\*</sup>KEMET Electronics Corp., <sup>†</sup>Penn State University, USA.
- IV.23 Modified Sodium Bismuth Titanate for High Temperature Capacitor Applications; *Conor Walsh*<sup>\*</sup>, *Gerald Wynick*<sup>\*</sup>, *Walter Schulze*<sup>\*</sup>, *Keith Bridger*<sup>†</sup>, *Arthur Cooke*<sup>†</sup>, and *James Weigner*<sup>#</sup>; <sup>\*</sup>Alfred University, <sup>†</sup>Active Signal Technologies, and <sup>#</sup>Lockheed Martin Maritime Sensors and Systems, USA.
- IV.24 New Relaxor Dielectrics for High Temperature Capacitors; *Craig Stringer*<sup>\*</sup>, *S.J. Zhang*<sup>\*</sup>, *T.R. Shrout*<sup>\*</sup>, *C.A. Randall*<sup>\*</sup>, *E. Alberta*<sup>†</sup>, *W. Hackenberger*<sup>†</sup>, and *G. Schwarze*<sup>#</sup>; <sup>\*</sup>The Pennsylvania State University, <sup>†</sup>TRS Technologies, Inc., and <sup>#</sup>NASA-Glenn Research Center, USA.
- IV.25 Characterization of PLZT Based Materials For High Energy Density Applications; *Bruce Tuttle*, *David Williams*<sup>\*</sup>, *Jill Wheeler*<sup>\*</sup>, *Luke Brewer*<sup>\*</sup>, *Paul Clem*<sup>\*</sup>, *Mark Rodriguez*<sup>\*</sup>, and *Geoffrey Brennecke*<sup>†</sup>; <sup>\*</sup>Sandia National Laboratories, <sup>†</sup>University of Illinois at Champaign, USA.

- IV.26 Dielectric Properties of Particles in Suspensions and Polymer Composites; *Abhishek Manohar, Fatih Dogan, Lynell Gilbert, and Thomas Schuman; University of Missouri-Rolla, USA.*
- IV.27 Optimization of Processing Parameters for Barium Strontium Titanate Glass Ceramics; *Edward P. Gorzkowski, M.-J. Pan, B. Bender, and C. C. M. Wu; Naval Research Laboratory, USA.*
- IV.28 Modeling of Field Distribution and Energy Storage in Diphasic Dielectrics; *Robert W. Schwartz, and Sandeep Patil; University of Missouri-Rolla, USA.*
- IV.29 Glass Ceramic Dielectrics; *Michael Lanagan, Jun Du, Chiping Wang, Beth Jones, Bhadri Rangarajan, Tony Perrotta, and Tom Shrout; The Pennsylvania State University, USA.*
- IV.30 Phase and Defect Equilibrium of BaTiO<sub>3</sub>: Revisited; *Clive A. Randall, S. il Lee, and Zi.K. Liu; The Pennsylvania State University, USA.*
- IV.31 Development of Fine Grain and High Tetragonality Barium Titanate Synthesized by Modified Hydrothermal Process; *S. Ogama, T. Shikada, K. Hidaka, and T. Ito; Sakai Chemical Industry Co., Ltd., Japan.*

### **Wednesday, November 9**

7:30 a.m.                    *Continental Breakfast (Patio)*

### **SESSION V. Thin Films, Material Science, and Applications**

Session Chairs:    Hajime Haneda, *National Institute for Research in Inorganic Materials (Japan)*  
                             Jan Allen, *U.S. Army Research Laboratory (USA)*

8:30–9:30 a.m.        *Plenary Lectures – Thin Films, Material Science, and Applications*

- PV.1    8:30– 9:00 a.m.     Bit Distribution and Reliability of Production-Worthy 1.5V FRAM  
                                 Embedded with 130nm, 5LM Copper CMOS Logic; *Scott Summerfelt\*, K.R. Udayakumar\*, K. Boku\*, K.A. Remack\*, J. Rodriguez\*, F.G. Celii\*, S. Aggarwal\*, G. Albrecht\*, Y. Obeng\*, J.S. Martin\*, L. Hall\*, L. Matz\*, B. Rathsack\*, H. McAdams\*, K.J. Taylor\*, R. Yonemoto\*, T.S. Moise\*, R. Bailey†, M. Depner†, G. Fox†, and J. Eliason†; \*Texas Instrument and †Ramtron International, USA.*

- PV.2    9:00– 9:30 a.m.     Growth of Potassium Niobate (KNbO<sub>3</sub>) Single Crystals for Piezoelectric Applications; *Masatoshi Adachi, Nao Fujita, Yoshiaki Norimatsu, and Tomoaki Karaki; Toyama Prefectural University, Japan.*

9:30 – 9:45 a.m.            *Break (Patio)*

9:45 a.m. – 12:00 p.m.     *Poster Summaries and Poster Viewing*

## **Thin Films, Material Science, and Applications**

- V.1 Dielectric and Optical Properties of Perovskite-type Artificial Superlattices; Takakiyo Harigai<sup>\*</sup>, Song-Ming Nam<sup>\*</sup>, Hirofumi Kakemoto<sup>\*</sup>, Satoshi Wada<sup>\*</sup>, Keisuke Saito<sup>†</sup>, and Takaaki Tsurumi<sup>\*</sup>; <sup>\*Tokyo Institute of Technology,,</sup> <sup>†BRUKER AXS K.K., Japan.</sup>
- V2. Fabrications of Relaxor PSN/PT thin films by PLD method and their characterization; Shutaro Asanuma<sup>\*</sup>, Yoshiaki Uesu<sup>\*</sup>, Mamoru Fukunaga<sup>\*</sup>, Raphael Haumont<sup>†</sup>, Brihim Dkhil<sup>†</sup>, Charlotte Malibert<sup>†</sup>, and Jean Michel Kiat<sup>†</sup>; <sup>†École Centrale Paris (France),</sup> <sup>\*Waseda University, Japan.</sup>
- V3. Radioisotope Power Generator Using Thin Film Piezoelectric Cantilevers; Ronald G. Polcawich, R. Duggirala<sup>†</sup>, E. Zakar<sup>\*</sup>, M. Dubey<sup>\*</sup>, and A. Lal<sup>†</sup>; <sup>\*U.S. Army Research Laboratory,</sup> <sup>†Cornell University, USA.</sup>
- V4. Emerging Piezoelectric PZT MEMS Devices, Madan Dubey, Ronald Polcawich, Eugene Zakar, Jeff Pulskamp, Luke Currano, Paul Amirtharaj, Richard Piekartz, John Conrad, and Derwin Washington, <sup>U.S. Army Research Laboratory, USA.</sup>
- V5. Fabrication of Ferroelectric-gate Transistors using YMnO<sub>3</sub> thin films; Takeshi Yoshimura, K. Haratake, R. Arai, N. Shigemitsu, K. Masuko, M. Nishijima, N. Fujimura; <sup>Osaka Prefecture University, Japan.</sup>
- V6. Synthesis and Properties of Intergrowth Bi<sub>4</sub>Ti<sub>3</sub>O<sub>12</sub>-SrBi<sub>4</sub>Ti<sub>4</sub>O<sub>15</sub> Ferroelectric Thin Films by Chemical Solution Deposition; Wataru Sakamoto, Keiichi Imada, Tetsuo Shimura, and Toshinobu Yogo; <sup>Nagoya University, Japan.</sup>
- V7. Thin Film Dielectrics for Embedded and Wireless Applications, Jon-Paul Maria<sup>\*</sup>, Jon F. Ihlefeld<sup>\*</sup>, Brian J. Laughlin<sup>\*</sup>, Mark D. Losego<sup>\*</sup>, and William J. Borland<sup>†</sup>; <sup>\*North Carolina State University,</sup> <sup>†Dupont Electronic Technologies, USA.</sup>
- V8. Preparation and Properties of Pb(Mg<sub>1/3</sub>Nb<sub>2/3</sub>)O<sub>3</sub> (50%)-PbTiO<sub>3</sub> (50%) Thin Films by Chemical Solution Deposition, Hiroshi Maiwa<sup>\*</sup> and Noboru Ichinose<sup>†</sup>; <sup>\*Shonan Institute of Technology,</sup> <sup>†Waseda University, Japan.</sup>
- V9. Evaluation of polar c-domain volume in tetragonal PbZr<sub>x</sub>Ti<sub>1-x</sub>O<sub>3</sub> thin films using polarized Raman spectroscopy, Ken Nishida<sup>\*</sup>, Minoru Osada<sup>†</sup>, Syunshuke Wada<sup>\*</sup>, Shoji Okamoto<sup>#</sup>, R. Ueno<sup>#</sup>, H. Funakubo<sup>#</sup>, and Takashi Katoda<sup>\*</sup>; <sup>\*Kochi University of Technology,</sup> <sup>†National Institute for Materials Science,</sup> <sup>#Tokyo Institute of Technology, Japan.</sup>
- V10. Reversible Domain Wall Motion Contributions to Rayleigh Behavior in Ferroelectric Films; Susan Trolier-McKinstry<sup>\*</sup>, Nazanin Bassiri Gharb<sup>\*</sup>, and Dragan Damjanovic; <sup>†Ceramic Laboratory Swiss Federal Institute of Technology, Lausanne (Switzerland),</sup> and <sup>\*The Pennsylvania State University, USA.</sup>
- V11. Bottom-Up Fabrication of Pb-Free Ferro-/Piezoelectric Films Using Complex Alkoxides; Kazumi Kato<sup>\*†</sup>, Kazuyuki Suzuki<sup>\*</sup>, Yiping Guo<sup>\*</sup>, Tatsuo Kimura<sup>\*</sup>, Kaori Nishizawa<sup>\*</sup>, Takeshi Miki<sup>\*</sup>; <sup>\*National Institute of Advanced Industrial Science & Technology,</sup> <sup>†Nagoya Institute of Technology, Japan.</sup>

- V12. Temperature dependency of  $P$ - $E$  hysteresis loops for rhombohedral PZT films; Hiroshi Funakubo, Akihiro Sumi, Hitoshi Morioka, Shoji Okamoto, and Shintaro Yokoyama; Tokyo Institute of Technology, Japan.
- V13. In Situ X-ray Scattering Studies of Electroded Epitaxial  $\text{PbTiO}_3$  Thin Films; Stephen K. Streiffer<sup>\*</sup>, G.B. Stephenson<sup>\*</sup>, D.D. Fong<sup>\*</sup>, P.H. Fuoss<sup>\*</sup>, J.A. Eastman<sup>\*</sup>, R.-V. Wang<sup>\*</sup>, F. Jiang<sup>\*</sup>, K. Latifi<sup>†</sup>, and Carol Thompson<sup>†</sup>; <sup>\*</sup>Argonne National Laboratory, <sup>†</sup>Northern Illinois University, USA.
- V14. Polarization Reversal Property of Ferroelectric Thin Film for Ferroelectric Memories; Masahiro Echizen and Yoichiro Masuda; Hachinohe Institute of Technology, Japan.
- V15. Investigation into Electrical Conduction Mechanisms of  $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$  Thin-Film Capacitors with Pt,  $\text{IrO}_2$  and  $\text{SrRuO}_3$  Top Electrodes; Yoichiro Masuda<sup>\*</sup> and Takashi Nozaka<sup>†</sup>; <sup>\*</sup>Hachinohe Institute of Technology, <sup>†</sup>Yokohama Denshi Seiko Co., Ltd., Japan.
- V 16. Ferroelectric and Piezoelectric Properties of Lanthanoid-Substituted  $\text{Bi}_4\text{Ti}_3\text{O}_{12}$  Thin Films Grown on (111)Pt and (100) $\text{IrO}_2$  Electrodes; Yutaka Adachi<sup>\*</sup>, Dong Su<sup>†</sup>, Paul Muralt<sup>†</sup>, and Nava Setter<sup>†</sup>; <sup>\*</sup>National Institute for Materials Science, Japan, and <sup>†</sup>Swiss Federal Institute of Technology (EPFL).

12:00–12:30 p.m.      Break

12:30-1:30 p.m.      Farewell Lunch (Patio)